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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/562,400 Confirmation No. : 8481
 First Named Inventor : Hiroshi KANNAN
 Filed : April 25, 2006
 TC/A.U. : 1763
 Examiner : To Be Assigned
 Docket No. : 010986.57272US
 Customer No. : 23911
 Title : Plasma Generation Method, Cleaning Method, and
 Substrate Processing Method

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT

Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

Sir:

On the attached copy of the Official Filing Receipt, it was noted that the first inventor's city and the title was incorrect. Please make changes to reflect that the correct city for the first inventor should be --Hachioji-shi-- instead of Hachioji-shi. The title should read as follows: --**Plasma Generation Method, Cleaning Method, and Substrate Processing Method**-- instead of **Plasma Generation Method, Cleaning and Processing Substrate**, as shown on the receipt.

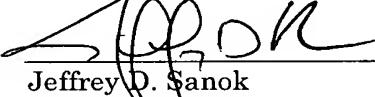
Attached is a Supplemental Application Data Sheet which reflects the corrected spelling of the first inventor's name and evidences the original filing of the title information.

Kindly return the "Corrected" Official Filing Receipt to the undersigned attorney of record.

Please charge any additional fee or credit any overpayment to the Deposit Account of Crowell & Moring, L.L.P., Account No. 05-1323, Docket No.: 010986.57272US.

Respectfully submitted,

May 9, 2007



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APPL NO.	FILING OR 371 (C) DATE	ART UNIT	FIL FEE REC'D	ATTY.DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/562,400	04/25/2006	1763	4830	010986.57272US	16	76	8

CONFIRMATION NO. 8481

23911
CROWELL & MORING LLP
INTELLECTUAL PROPERTY GROUP
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WASHINGTON, DC 20044-4300

CORRECTED FILING RECEIPT



OC000000022003903

Date Mailed: 01/16/2007

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Hachioji-shi

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Assignment For Published Patent Application

TOKYO ELECTRON LIMITED, Tokyo, JAPAN

Power of Attorney: The patent practitioners associated with Customer Number 23911.

Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP04/09026 06/25/2004

Foreign Applications

JAPAN 2003-185160 06/27/2003

JAPAN 2003-185161 06/27/2003

DOCK 6/14/06

4/10/06

If Required, Foreign Filing License Granted: 07/01/2006

One Date

The country code and number of your priority application, to be used for filing abroad under the Paris Convention, is **US10/562,400**

Projected Publication Date: Not Applicable

Non-Publication Request: No

Early Publication Request: No

Title

method,
Plasma generation method, cleaning and processing substrate
^ substrate processing method

Preliminary Class

216

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